

MORRISON & FOERSTER LLP

Attorneys at Law
555 West Fifth Street
Suite 3500
Los Angeles, California 90013-1024
Telephone: (213) 892-5200
Facsimile: (213) 892-5454

To:

NAME:	FACSIMILE:	TELEPHONE:
Examiner Jeffrey Shapiro U.S. Patent and Trademark Office	(703) 746-3851	(703) 308-3423

FROM: Glenn M. Kubota**DATE:** December 4, 2003

Number of pages with cover page: 8 Client/matter: 19937.2001800

Preparer of this slip has confirmed that facsimile number given is correct: 9108/gmk3**CAUTION - CONFIDENTIAL**

This facsimile contains confidential information which may also be privileged. Unless you are the addressee (or authorized to receive for the addressee), you may not copy, use, or distribute it. If you have received it in error, please advise Morrison & Foerster LLP immediately by telephone or facsimile and return it promptly by mail.

Comments:

Please see attached.

PATENT
Docket No. 199372001800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the application of:

Akira KOGUCHI

Serial No.: 09/611,635

Filing Date: July 7, 2000

For: CONTAINER HANDLING SYSTEM
FOR SUBSTRATE PROCESSING
APPARATUS AND METHOD OF
HANDLING CONTAINERS

Examiner: Jeffrey A. Shapiro

Group Art Unit: 3653

PROPOSED CLAIM AMENDMENTS

Dear Examiner Shapiro:

Here are the amendments I will be proposing during the interview at 1 p.m. on Monday, Dec. 8, 2003. For clarity, I have removed all previously canceled and withdrawn claims and rearranged the order of the claims (but not the numbers) so that independent claims 24 and 25 appear at the beginning, because all claims except claims 28-30 now depend from claims 24 and 25.

With the limitations added by the proposed amendments, we believe that the present invention can be distinguished from Davis, because Davis does not disclose a sensing device coupled to the movable table as in the present invention, and neither Davis nor any of the other cited references disclose a cut-away area shaped and sized to allow the sensing device uninterrupted access to the substrates as the movable table is moved perpendicular to the substrates into a first position under the first stage, as in the present invention.

See you on Monday!

Regards,

Glenn M. Kubota

1a-695655

PAGE 28 * RCVD AT 12/4/2003 5:04:19 PM [Eastern Standard Time] * SVR:USPTO-EFXRF-2/5 * DNIS:7463851 * CSID:949 251 0900 * DURATION (mm:ss):03:06